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(71) Applicant (for all designated States except US):
TEL-AVIV UNIVERSITY FUTURE TECHNOLOGY DEVELOPMENT L.P. (IL/IL); P.O. Box 39040,
69978 Tel-Aviv (IL).

(72) Inventors; and

(75) Inventors/Applicants (for US only): **NATHAN, Menachem** (IL/IL); 5 Arie Suslik Street, Tel Aviv 69359 (IL).

PELED, Emanuel (IL/IL); 25 Hanote's Street, 40500
Even Yehuda (IL). **GOLODNITSKY, Diana** (IL/IL);
16/6 Hanagid Street, 75482 Rishon LeTzion (IL). **YUFIT,**
Vladimir (IL/IL); 14/19 Michashvili Street, 77535 Ash-
dod (IL).

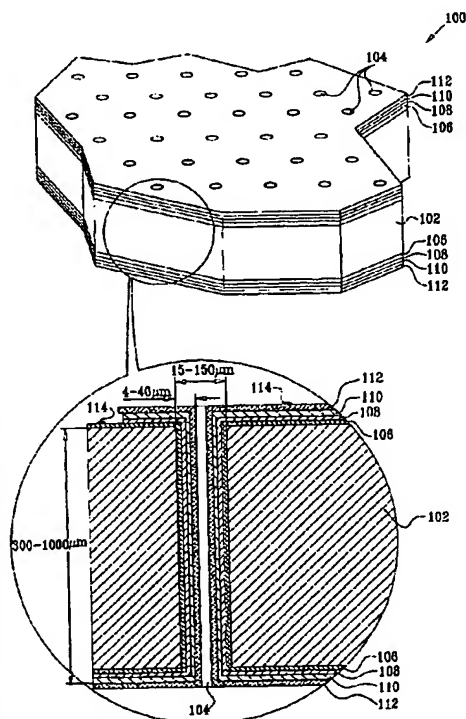
(74) Agents: **SANFORD T. COLB & CO.** et al.; P.O. Box
2273, 76122 Rehovot (IL).

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[Continued on next page]

(54) Title: **THIN-FILM CATHODE FOR 3-DIMENSIONAL MICROBATTERY AND METHOD FOR PREPARING SUCH CATHODE**



(57) Abstract: A method for producing a microbattery (100) including providing a conductive substrate (102), forming a thin film cathodic layer (108) on at least one surface of the conductive substrate, subsequently forming a thin film electrolyte layer (110) over the cathodic layer and subsequently forming a thin film anodic layer (112) over the electrolyte layer.

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A. CLASSIFICATION OF SUBJECT MATTER
IPC 7 H01M10/40 H01M4/04 H01M4/02 H01M4/58 C25D9/04

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B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)
IPC 7 H01M C25D

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal, WPI Data, PAJ

C. DOCUMENTS CONSIDERED TO BE RELEVANT

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Y	page 2, line 11 - page 3, line 8 claims 9,10	4-6, 13, 16-18, 25, 29-31, 38, 41-43, 50

☒ Further documents are listed in the continuation of box C.

☒ Patent family members are listed in annex.

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X document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone

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Name and mailing address of the ISA

European Patent Office, P.B. 5818 Patentlaan 2
NL - 2280 HV Rijswijk
Tel. (+31-70) 340-2040, Tx. 31 651 epo nl,
Fax: (+31-70) 340-3016

Authorized officer

Standaert, F

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International Application No
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C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT		
Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
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